

Form PTO-1449 (modified)

Atty. Docket No.

2000.109000/DE0133

Serial No.

10/666,195

List of Patents and Publications for Applicant's

INFORMATION DISCLOSURE STATEMENT

(Use several sheets if necessary)

Applicant

Gerd Marxsen, Axel Preusse, Markus Nopper and Frank Mauersberger

Filing Date:

September 19, 2003

Group:

~~2811~~ 2813

U.S. Patent Documents

See Page 1

Foreign Patent Documents

See Page 1

Other Art

See Page 1

U.S. Patent Documents

Exam. Init.	Ref. Des.	Document Number	Date	Name	Class	Sub Class	Filing Date of App.
JMS	A1	2001/0015321 A1	8/23/01	Reid <i>et al.</i>	205	103	
JMS	A2	6,346,479 B1	2/12/02	Woo <i>et al.</i>	438	687	
JMS	A3	6,350,364 B1	2/26/02	Jang	205	118	
JMS	A4	2002/0195351 A1	12/26/02	Lu <i>et al.</i>	205	574	

Foreign Patent Documents

Exam. Init.	Ref. Des.	Document Number	Date	Country	Class	Sub Class	Translation Yes/No
JMS	B1	WO 03/009361 A2	1/30/03	PCT	H01L	21/288	Yes

Other Art (Including Author, Title, Date Pertinent Pages, Etc.)

Exam. Init.	Ref. Des.	Citation
JMS	C1	Cerisier <i>et al.</i> , "Growth Mode of Copper Films Electrodeposited on Silicon from Sulfate and Pyrophosphate Solutions," <i>J. Electrochem. Soc.</i> , 146:2156-62, 1999
JMS	C2	Data Sheets (in German) "Polyether" and "Polyalkylene Glycol", 2003
JMS	C3	Reid <i>et al.</i> , "Factors Influencing Damascene Feature Fill Using Copper PVD and Electroplating," <i>Solid State Technology</i> , pp. 86-103, July 2000
JMS	C4	Hong <i>et al.</i> , "Developing Metrology for Controlling Cu-electroplating Additives," <i>Solid State Technology</i> , pp. 57-59, October 2002
JMS	C5	Banerjee <i>et al.</i> , "Simultaneous Optimization of Electroplating and CMP for Copper Processes," <i>Solid State Technology</i> , pp. 83-88, November 2001
JMS	C6	Smekalin <i>et al.</i> , "Tuning the Process Flow to Optimize Copper CMP," <i>Solid State Technology</i> , pp. 107-112, September 2001

EXAMINER:

DATE CONSIDERED:

2/15/05

EXAMINER: INITIAL IF REFERENCE CONSIDERED, WHETHER OR NOT CITATION IS IN CONFORMANCE WITH MPEP609; DRAW LINE THROUGH CITATION IF NOT IN CONFORMANCE AND NOT CONSIDERED. INCLUDE COPY OF THIS FORM WITH NEXT COMMUNICATION TO APPLICANT.

Form PTO-1449 (modified)

SEP 07 2004

Atty. Docket No.
2000.109000/DE0133Serial No.
10/666,195

List of Patents and Publications for Applicant's

INFORMATION DISCLOSURE STATEMENT

(Use several sheets if necessary)

Filing Date:
September 19, 2003Group:
~~2811~~ 2813U.S. Patent Documents
See Page 1Foreign Patent Documents
See Page 1Other Art
See Page 1

U.S. Patent Documents

Exam. Init.	Ref. Des.	Document Number	Date	Name	Class	Sub Class	Filing Date of App.
<i>AM</i>	A5	6,179,691 B1	1/30/01	Lee <i>et al.</i>	451	41	—
<i>AM</i>	A6	2002/0175080 A1	11/28/02	Teerlinck <i>et al.</i>	205	291	—
	A7						
	A8						
	A9						

Foreign Patent Documents

Exam. Init.	Ref. Des.	Document Number	Date	Country	Class	Sub Class	Translation Yes/No
<i>AM</i>	B2	EP 1 191 128 A2	3/27/02	Europe	C25D	5/08	Yes
	B3						
	B4						

Other Art (Including Author, Title, Date Pertinent Pages, Etc.)

Exam. Init.	Ref. Des.	Citation
<i>AM</i>	C1	
	C2	
	C3	

EXAMINER:

DATE CONSIDERED:

2/15/05

EXAMINER: INITIAL IF REFERENCE CONSIDERED, WHETHER OR NOT CITATION IS IN CONFORMANCE WITH MPEP609; DRAW LINE THROUGH CITATION IF NOT IN CONFORMANCE AND NOT CONSIDERED. INCLUDE COPY OF THIS FORM WITH NEXT COMMUNICATION TO APPLICANT.